Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. – 4. (Canceled)

5. (Currently Amended) A system made up of at least one substrate conveying module and at least one workstation which has several side walls, substrates being exchangeable between the substrate conveying module and the workstation, wherein the workstation has, on at least two different side walls, kinematic coupling connecting elements that coact with corresponding kinematic coupling connecting elements on at least one side wall of the substrate conveying module to provide for an immovable connection between the workstation and the substrate conveying module while simultaneously automatically aligning the workstation with the substrate conveying module.

6. (Canceled)

7. (Currently Amended) ~~The system as defined in Claim 5,~~ A system made up of at least one substrate conveying module and at least one workstation which has several side walls, substrates being exchangeable between the substrate conveying module and the workstation, wherein the workstation has, on at least two different side walls, kinematic coupling connecting elements that coact with corresponding kinematic coupling connecting elements on at least one side wall of the substrate conveying module; wherein the substrate conveying module has one or more load ports for the loading and unloading of the substrates into and from the substrate conveying module.

8. (Previously Presented) The system as defined in Claim 5, wherein the workstation is provided for the inspection, measurement, or processing of the substrates.

9. (Previously Presented) The system as defined in Claim 5, wherein the workstation comprises a permanently set transfer point for the exchange of the substrates between the substrate conveying module and the workstation.

10. – 11. (Canceled)

12. (Previously Presented) The system as defined in Claim 5, wherein the substrate conveying module has kinematic coupling connecting elements on at least two different side walls.

13. (Previously Presented) The system as defined in Claim 12, wherein the substrate conveying module has at least one load port for the loading and unloading of said substrates into and from the substrate conveying module,

wherein said workstation is configured to perform a function comprising at least one of inspecting, measuring, and processing said substrates,

wherein each of said at least two different side walls of said workstation is connectable to each of said at least two different side walls of said substrate conveying module so as to provide for at least four distinct connection configurations between said workstation and said substrate conveying module, and

wherein, in each of said at least four configurations, said system is configured to move said substrates from said at least one load port to said workstation to perform said function.

14. (Previously Presented) The system as defined in Claim 5, wherein the at least two different side walls are adjacent.

15. (Previously Presented) The system as defined in Claim 5, wherein the workstation is configured to exchange said substrates with said substrate conveying module via only one of said at least two different side walls at a time.

16. (Previously Presented) The system as defined in Claim 5, wherein said substrate conveying module is a first substrate conveying module,

wherein said system further comprises a second substrate conveying module,

wherein each of said substrate conveying modules has kinematic coupling connecting elements on at least two different side walls,

wherein each of said substrate conveying modules is connected to said workstation, and

wherein said system is configured so that substrates are exchanged from said first substrate conveying module to said workstation, and subsequently from said workstation to said second substrate conveying module.

17. (New) The system as defined in Claim 5, wherein at least one kinematic coupling connecting element comprises a pin on at least one of the workstation and the substrate conveying module and wherein the corresponding kinematic coupling connecting element on the other of the at least one of the workstation and the substrate conveying module comprises a hole, wherein the pin encounters the hole while the respective kinematic coupling connecting elements coact.

18. (New) The system as defined in Claim 17, wherein the pin is cylindrical.

19. (New) The system as defined in Claim 17, wherein the hole is elongated.

20. (New) The system as defined in Claim 5, wherein the substrate conveying module has one or more load ports for the loading and unloading of the substrates into and from the substrate conveying module.